

FIRST INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1 of 1

Complete if Known

Application Number	Unassigned
Filing Date	December 3, 2003
First Named Inventor	Man WONG et al
Examiner Name	Unassigned
Attorney Docket Number	016660-188

U.S. PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
<i>[Signature]</i>	4,533,795		Baumhauer, Jr., et al	08-06-1985
<i>[Signature]</i>	4,558,184		Busch-Vishniac et al	12-10-1985
<i>[Signature]</i>	5,573,679		Mitchell et al	11-12-1996
<i>[Signature]</i>	5,684,324		Bernstein	11-04-1997
<i>[Signature]</i>	6,479,878		Okawa et al	11-12-2002

FOREIGN PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Country	Date of Publication (MM-DD-YYYY)	Translation	
					Yes	No

NON-PATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
<i>[Signature]</i>	Bergqvist, J., et al., "Capacitive Microphone with a Surface Micromachined Backplate Using Electroplating Technology", <i>Journal of Microelectromechanical Systems</i> , Vol. 3, No. 2, June 1994, pp. 69-75, IEEE (1994).
<i>[Signature]</i>	Zou, Q.B., et al, "Design and Fabrication of a Novel Integrated Floating-Electrode-'Electret'-Microphone (FEEM)", <i>Proceedings of the 11th International Workshop on Micro Electro Mechanical Systems</i> , January 1998, pp. 586-590, IEEE (1998).
<i>[Signature]</i>	Murphy, P., et al, "Subminiature Silicon Integrated Electret Condenser Microphone", <i>6th International Symposium on Electrets (ISE 6) Proceedings</i> , 1988, abstract.

4/14/05